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Applicant: Wayne A. Bonin

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2605
2212LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION
DISCLOSURE STATEMENT

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
<i>Dm</i>	AA	3,307,407	03/07/67	Berg et al.	73	432
<i>Dm</i>	AB	3,314,493	04/18/67	Kennedy	177	210
<i>Dm</i>	AC	3,418,546	12/24/68	Beavers et al.	317	246
<i>Dm</i>	AD	4,040,118	08/02/77	Johnston	361	283
<i>Dm</i>	AE	4,089,036	05/09/78	Geronime	361	283
<i>Dm</i>	AF	4,196,632	04/08/80	Sikorra	73	718
<i>Dm</i>	AG	4,237,989	12/09/80	Lewis	177	210
<i>Dm</i>	AH	4,294,321	10/13/81	Wittlinger et al.	177	210 FP
<i>Dm</i>	AI	4,310,806	01/12/82	Ogasawara	331	40
<i>Dm</i>	AJ	4,479,392	10/30/84	Froeb et al.	73	862.68
<i>Dm</i>	AK	4,523,473	06/18/85	Chamuel	73	643
<i>Dm</i>	AL	4,523,474	06/18/85	Browne et al.	73	724
<i>Dm</i>	AM	4,550,617	11/05/85	Fraignier et al.	73	862.04
<i>Dm</i>	AN	4,685,678	08/11/87	Frederiksen	273	148
<i>Dm</i>	AO	4,694,687	09/22/87	Bonin et al.	73	116
<i>Dm</i>	AP	4,699,000	10/13/87	Lashmore et al.	73	81
<i>Dm</i>	AQ	4,750,082	06/07/88	Gerety	361	283
<i>Dm</i>	AR	4,820,051	04/11/89	Yanagisawa et al.	356	378
<i>Dm</i>	AS	4,848,141	07/18/89	Oliver et al.	73	81
<i>Dm</i>	AT	4,922,444	05/01/90	Baba	364	566
<i>Dm</i>	AU	4,970,374	11/13/90	Ueda et al.	219	518
<i>Dm</i>	AV	5,006,952	04/09/91	Thomas	361	283
<i>Dm</i>	AW	5,065,103	11/12/91	Slinkman et al.	324	458
<i>Dm</i>	AX	5,083,091	01/21/92	Frick et al.	324	678
<i>Dm</i>	AY	5,092,174	03/03/92	Reidemeister et al.	73	517

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Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
D4- AG	5,115,291	05/19/92	Stokes	357	26	
D4- BA	5,128,671	07/07/92	Thomas, Jr.	341	20	
D4- BB	5,134,886	08/04/92	Ball	73	718	
D4- BC	5,174,159	12/29/92	Jacobsen et al.	73	767	
D4- BD	5,193,383	03/16/93	Burnham et al.	73	105	
D4- BE	5,255,562	10/26/93	Yamamoto et al.	73	160	
D4- BF	5,305,633	04/26/94	Weissenbacher et al.	73	82	
D4- BG	5,359,879	11/01/94	Oliver et al.	73	7	
D4- BH	5,381,300	01/10/95	Thomas et al.	361	280	
D4- BI	5,383,364	01/24/95	Takahashi et al.	73	517R	
D4- BJ	5,406,832	04/18/95	Gamble et al.	73	105	
D4- BK	5,412,327	05/02/95	Meinen	324	686	
D4- BL	5,421,213	06/06/95	Okada	73	862.04 3	
D4- BM	5,424,650	06/13/95	Frick	324	688	
D4- BN	5,437,196	08/01/95	Okada	73	862	
D4- BO	5,492,020	02/20/96	Okada	73	862	

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	Document No.	Date	Country	Class	Sub Class	Translation Yes No
D4- BP	2 189 607 A	10/28/87	United Kingdom	—	—	
D4- BQ	1-195338	08/07/89	Japan	—	—	
D4- BR	2-231546	09/13/90	Japan	—	—	
D4- BS	WO 88/00691	01/28/88	PCT	—	—	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

D4- BT	Wickramasinghe, "Scanned-Probe Microscopes", <u>Scientific American</u> , October, 1989, pp. 98-105.
D4- BU	Grigg, et al., "Tip-sample forces in scanning probe microscopy in air and vacuum", <u>J. Vac. Sci. Technol. A</u> , Vol. 10, No. 4, Jul/Aug, 1992, pp. 680-83.
D4- BV	Heerens, "Application of capacitance techniques in sensor design", <u>J. Phys. E. Sci. Instrum.</u> , Vol. 19, 1986, pp. 897-906.

Paul H. L.

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DW	BW	Nishibori et al., "Ultra-Microhardness of Vacuum-Deposited Films in Ultra-Microhardness Tester", <u>Thin Solid Films</u> , Vol. 48, 1978, pp. 325-331.
DW	BX	Kamamoto et al., "Mechanical Properties of Thin Films measurements of Ultramicroindentation Hardness Young's Modulus and Internal Stress",
DW	1996	Yanagisawa et al., "An Ultramicro Indentation Hardness Tester and Its Application to Thin Films", <u>Lubrication Engineering</u> , Vol. 45, January, 1987, pp. 56.
DW	BZ	Newey et al., "An ultra-low-load penetration hardness tester", <u>J. Phys. E. Sci. Instrum.</u> , Vol. 15, 1982, pp. 119-122.
DW	CA	Wierenga et al., "Ultramicroindentation apparatus for the mechanical characterization of thin films", <u>J. Appl. Phys.</u> , Vol. 55, No. 12, June 15, 1984, pp. 42244-47.
DW	CB	Wierenga et al., "Ultramicrohardness Experiments on Vapour-Deposited Films of Pure Metals and Alloys", <u>Thin Solid Films</u> , Vol. 119, 1984, pp. 375-82.
DW	CC	Burnham et al., "Measuring the nanomechanical properties and surface forces of materials using an atomic force microscope", <u>J. Vac. Sci. Technol. A</u> , Vol. 7, No. 4, Jul/Aug, 1989, pp. 2906-13.
DW	CD	Oliver et al., "Thin Film Characterization Using a Mechanical Properties Microprobe", <u>Thin Solid Films</u> , Vol. 153, 1987, pp. 185-96.
DW	CE	Wu, "Microscratch and load relaxation tests for ultra-thin films", <u>J. Mater. Res.</u> , Vol. C, No. 2, February, 1991, pp. 407-26.
DW	CF	Holman et al., "Using capacitive sensors for in situ calibration of displacements in a piezo-driven translation stage of an STM", <u>Sensors and Actuators A</u> , Vol. 36, 1993, pp. 37-42.
DW	CG	Weihhs et al., "Mechanical deflection of cantilever microbeams: A new technique for testing the mechanical properties of thin films", <u>J. Mater. Res.</u> , Vol. 3, No. 5, Sept/Oct. 1988, pp. 931-942.

EXAMINER: *DW*

DATE CONSIDERED: 18 November 1996

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.